00862.023135



### **PATENT APPLICATION**

### IN PRESONTED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	)
	: Examiner: D. J. Rutledge
Kotaro AKUTSU et al.	)
	: Group Art Unit: 2851
Application No.: 10/617,682	)
	: Confirmation No.: 4128
Filed: July 14, 2003	)
	•
For: ELECTRON BEAM EXPOSURE APPARATUS	) January 10, 2004
AND SEMICONDUCTOR DEVICE	: (Monday)
MANUFACTURING METHOD	)

## Mail Stop Amendment

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Transmitted herewith is an Amendment in the above-identified application.

X No additional fee is required.

The fee has been calculated as shown below:

CLAIMS AS AMENDED						
	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL CLAIMS	15	MINUS	20	= 0	x \$25 \$50	\$0.00
INDEP. CLAIMS	2	MINUS	3	= 0	x \$100 \$200	\$0.00
Fee for Multiple Dependent claims \$180/\$360						
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT					\$0.00	

	A check in the amount of \$ is enclosed.
	Charge \$ to Deposit Account No. 06-1205. A duplicate of this sheet is enclosed.
X	Any prior general authorization to charge an issue fee under 37 CFR 1.18 to Deposit Account No. 06-1205 is hereby revoked. The Commissioner is hereby authorized to charge any additional fees under 37 CFR 1.16 and 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 06-1205. A duplicate of this paper is enclosed.
	A check in the amount of \$ to cover the fee for a month extension is enclosed.
	A check in the amount of \$ to cover the Information Disclosure Statement fee is enclosed.
X	Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our address given below.
	Respectfully submitted,
	Attorney for Applicants Steven E. Warner Registration No. 33,326

FITZPATRICK, CELLA, HARPER & SCINTO 30 Rockefeller Plaza
New York, New York 10112-3801
Facsimile: (212) 218-2200

SEW/eab

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00862.023135

### **PATENT APPLICATION**

#### IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	)
	: Examiner: D. J. Rutledge
Kotaro AKUTSU et al.	)
	: Group Art Unit: 2851
Application No.: 10/617,682	)
	: Confirmation No.: 4128
Filed: July 14, 2003	)
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For: ELECTRON BEAM EXPOSURE APPARATUS	) January 10, 2004
AND SEMICONDUCTOR DEVICE	: (Monday)
MANUFACTURING METHOD	)

# **Mail Stop Amendment**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

#### **AMENDMENT**

Sir:

In response to the Official Action dated October 8, 2004, please amend the above-identified application as follows: